

Title (en)

METHOD FOR IMPEDANCE MATCHING, IMPEDANCE MATCHING ARRANGEMENT AND PLASMA SYSTEM

Title (de)

VERFAHREN ZUR IMPEDANZANPASSUNG, IMPEDANZANPASSUNGSANORDNUNG UND PLASMASYSTEM

Title (fr)

PROCÉDÉ D'ADAPTATION D'IMPÉDANCE, AGENCEMENT D'ADAPTATION D'IMPÉDANCE ET SYSTÈME À PLASMA

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Application

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Abstract (en)

[origin: WO2022184713A1] The invention relates to a method for impedance matching using an impedance matching network (2) comprising an input (3) for connecting an RF power generator (5) and an output (4) for connection to a load (6) that has at least one first and one second series-connected matching stage (10, 12) each having a variable reactance (XP, XS), the method comprising the following steps: a) measuring an input impedance (Zin), b) ascertaining an intermediate impedance (Zinter) from the measured input impedance (Zin) and at least one current state value of at least one of the matching stages, c) ascertaining a target change value (dXP, dXS) for at least one reactance (XP, XS) of a matching stage (10, 12) from the intermediate impedance (Zinter) and a model of the impedance matching network (2), d) changing the state of at least one of the matching stages (10, 12) based on the target change value (dXP, dXS), e) repeating steps a) to d).

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